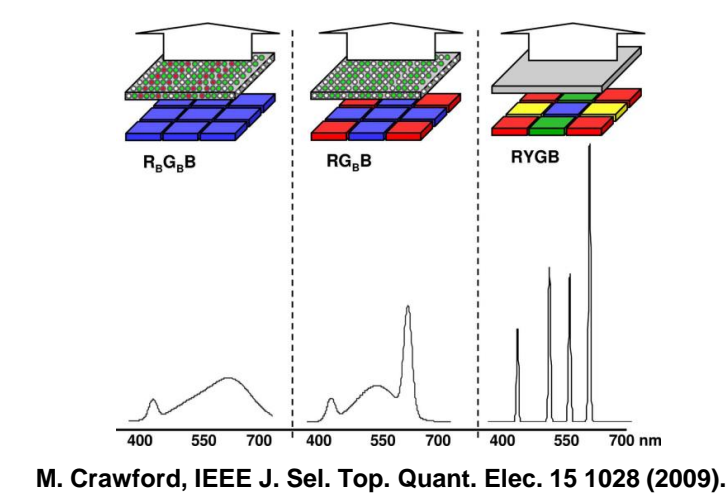
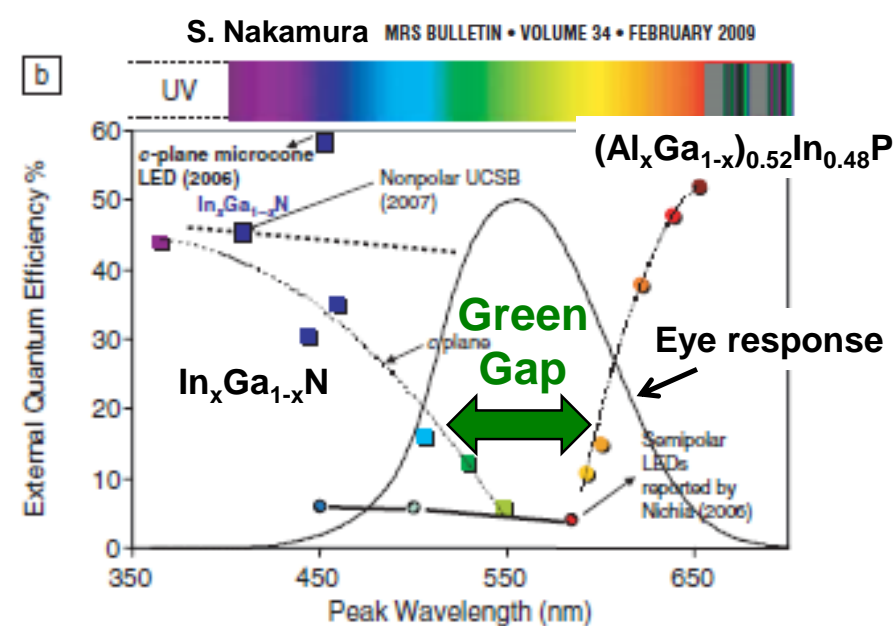


# Goal: Increase EQE of InGaN 540 nm LEDs through defect reduction

**Objective:** Increase efficiency of deep green-emitting InGaN/GaN LEDs through InGaN defect reduction



M. Crawford, IEEE J. Sel. Top. Quant. Elec. 15 1028 (2009).  
Multichip LEDs promise better efficiency than phosphor-converted LEDs, but...



**Goal:** Mitigate InGaN defects in InGaN/GaN MQWs

**Challenge:** Develop *quantitative* defect spectroscopy for  $\text{In}_{0.2}\text{Ga}_{0.8}\text{N}$  epilayers

## Major Project Milestones:

- *Develop* quantitative defect spectroscopy for nanoscale  $\text{In}_x\text{Ga}_{1-x}\text{N}$  films
- *Reduce* defect incorporation and improve IQE for 540 nm InGaN QWs
- *Improve* EQE for 540 nm InGaN LEDs via reduced defect incorporation

## Problems to be addressed:

- Understand  $\text{In}_x\text{Ga}_{1-x}\text{N}$  ( $x > 0.15$ ) deep level defect activity
- Correlate defect incorporation and  $\text{In}_x\text{Ga}_{1-x}\text{N}$  growth parameters
- Determine impact of defects on LED External Quantum Efficiency (EQE)

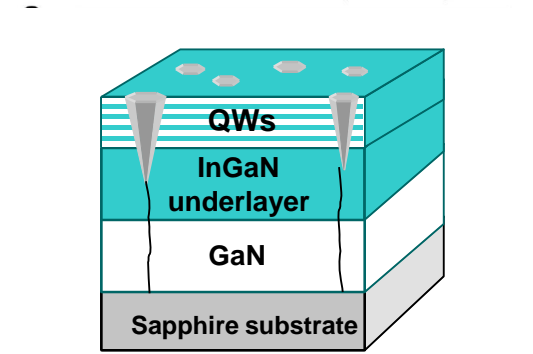
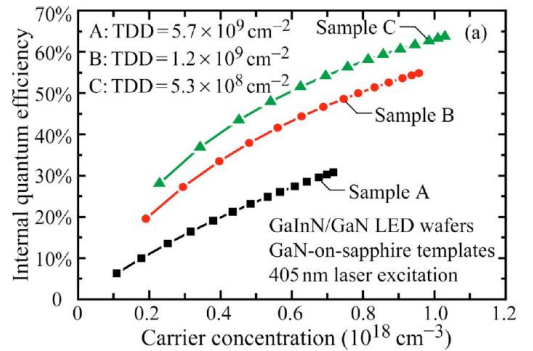
## Expected Benefits to SSL:

- Enhanced EQE of (540 nm) LEDs
- Increase both luminous efficiency and CRI for RGB color-mixing
- Accelerate white SSL penetration into lighting market

# Impact of InGaN Defects on Efficiency

## Impact of defects on radiative efficiency

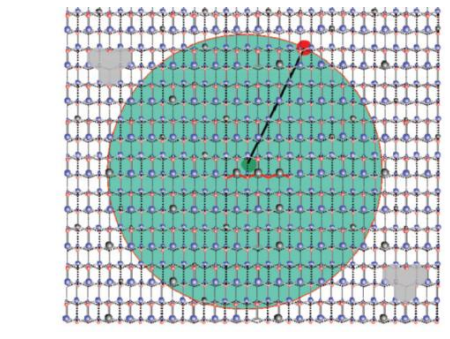
### Extended defects and EQE



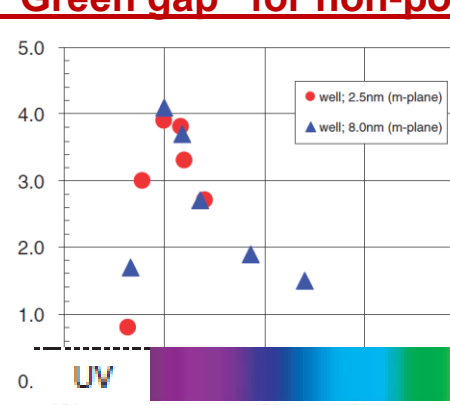
Internal quantum efficiency and nonradiative recombination coefficient of GaN/InGaN multiple quantum wells with different dislocation densities

Chichibu et al. Philos. Mag. 87 2019 (2007)

### Point defects and EQE

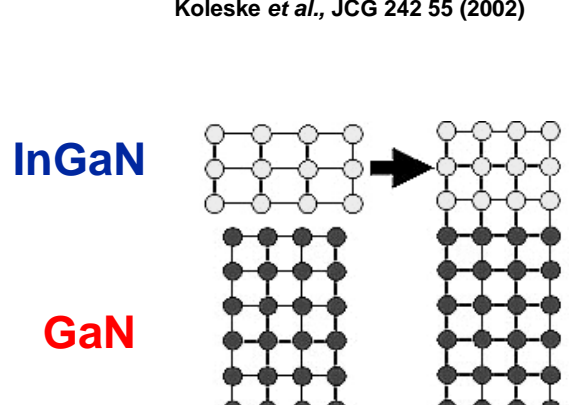
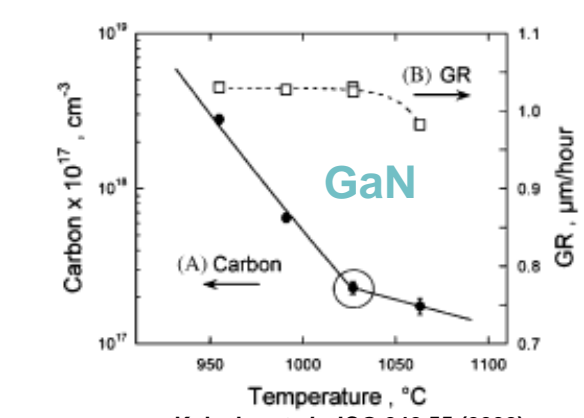


“Green gap” for non-polar



Yamada et al. Appl. Phys. Exp. 1 041101 (2008)

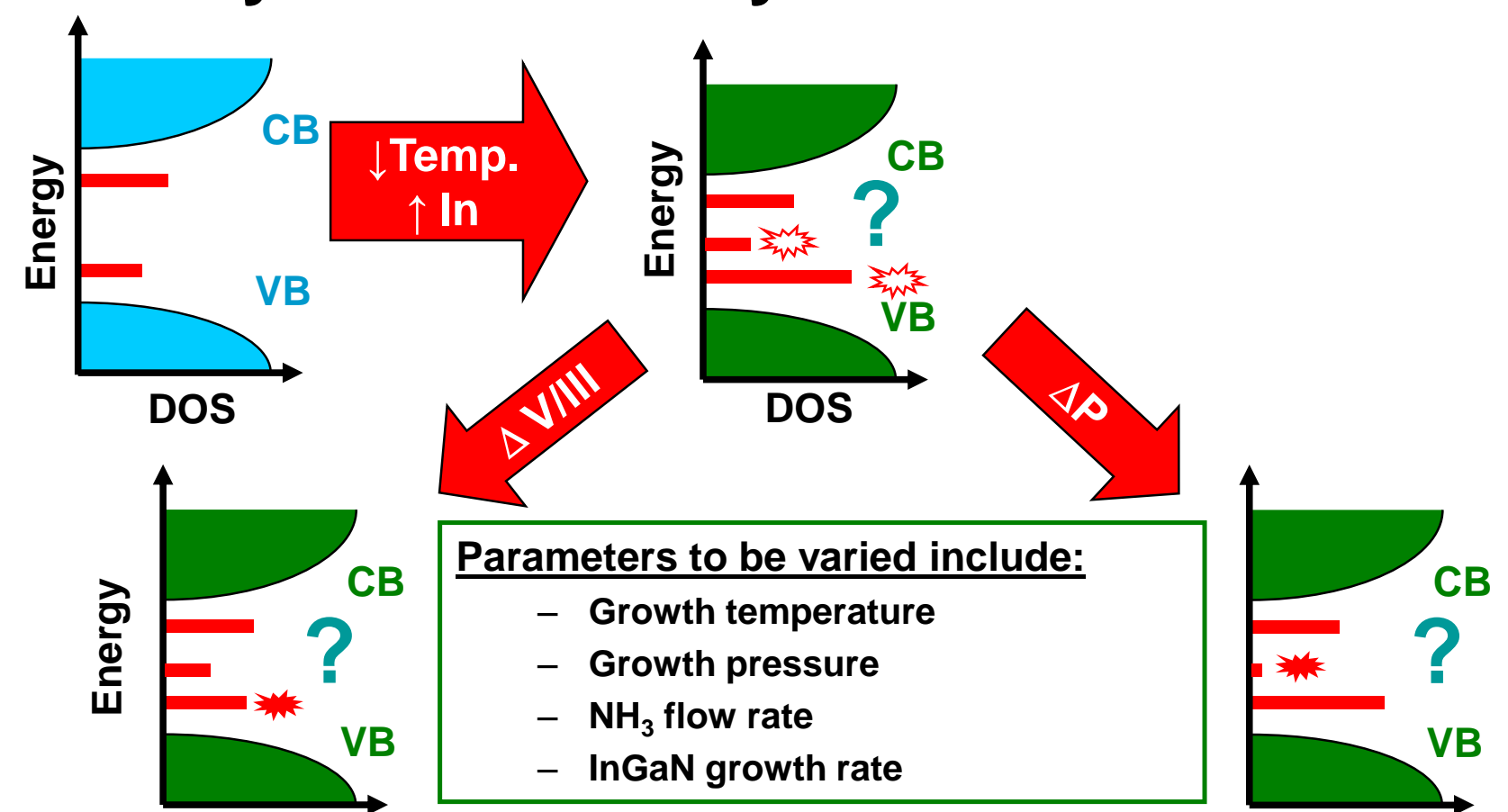
### Growth conditions and strain



Koleske et al., JCG 242 55 (2002)

- How to connect InGaN growth conditions, defects and EQE?
- **Solution:** Adapt Deep Level Optical Spectroscopy for InGaN LEDs

## Systematic study of InGaN defects



- Need method to *quantify* deep level defect energy and density
- Correlate defect studies with EQE
- Vary growth parameters to mitigate critical defects and improve EQE

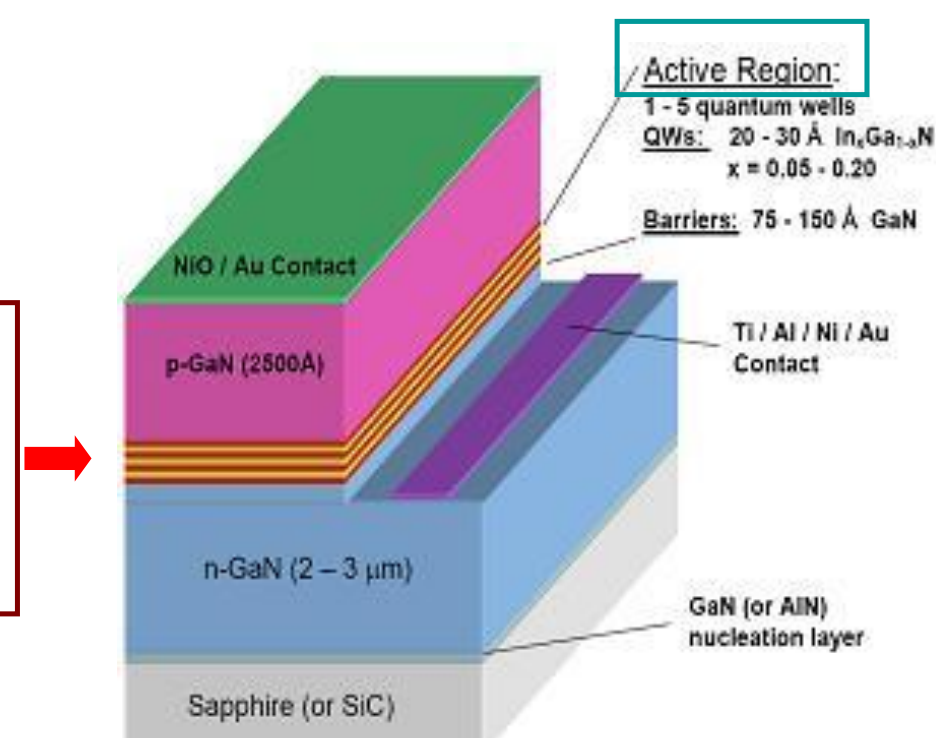
# Challenge and Solution

## Problem: How to study InGaN LED defects?

LEDs are complicated nanoscale, multi-heterolayer, bipolar devices with strongly varying (In,Al,Ga)N alloy compositions

Defects located near the optically active MQW region are most critical to LED radiative efficiency

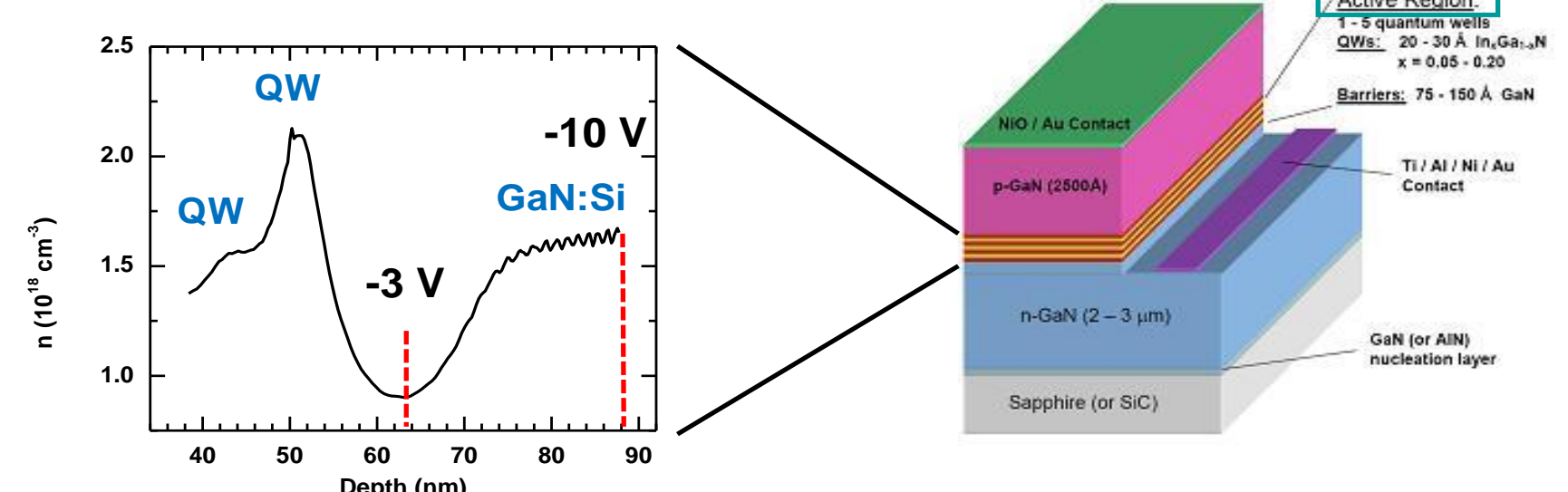
How to isolate and study defects in the *nanoscopic* MQW region embedded in a microscopic LED?



## Solution: Depth-resolved Deep Level Optical Spectroscopy

### Deep Level Optical Spectroscopy (DLOS)!

- Photocapacitance technique
  - *Sub-band gap optical stimulation* to photoionize defect levels (reverse of PL)
  - *Quantify non-radiative* defect level energy and density (difficult for PL)
  - Depletion region technique for *depth resolution*



- DLOS depth resolution from pin LED junction
- Junction contains the MQW region and the n-GaN region
- Use electrical bias to emphasize defects in either the MQW or n-GaN regions



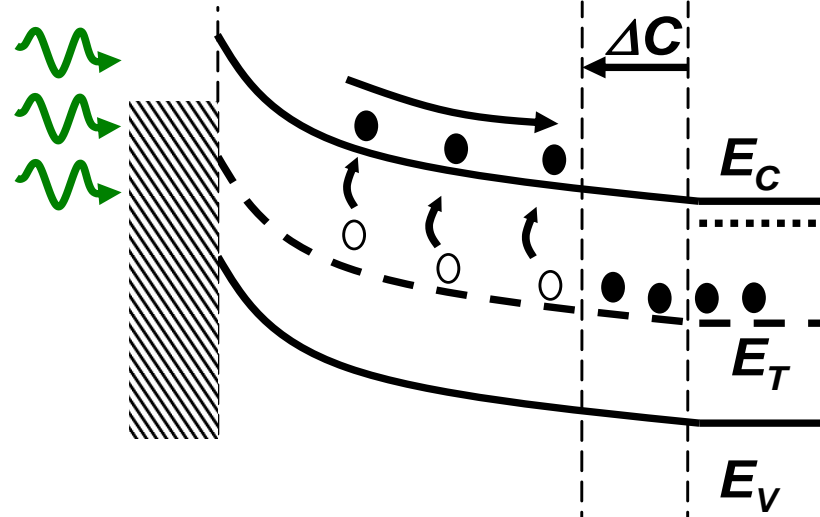
# Concept of Depth-resolved DLOS

## Fundamentals of DLOS

Sub-band gap, monochromatic light to scan defect states

### Steady-state photocapacitance

- Depletion region technique
- $\Delta C$  indicative of  $N_t$
- (+) onset  $\rightarrow$  Majority carrier emission
- (-) onset  $\rightarrow$  Minority carrier emission



### Deep Level Optical Spectroscopy<sup>1</sup>

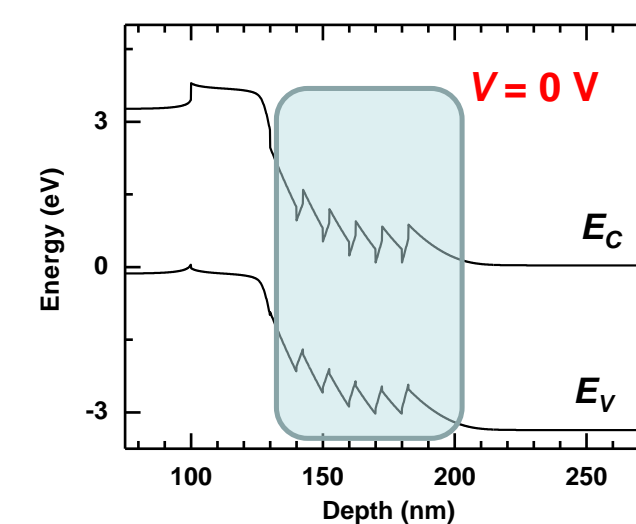
- Measures deep level optical cross-section  $\sigma^0$ :
  - $dC(t)/dt|_{t=0} \propto \sigma^0(h\nu)\Phi(h\nu)$
- Fitting  $\sigma^0(h\nu)$  to model<sup>2</sup> extracts deep level defect properties
  - Optical ionization energy  $E^0$
  - Franck-Condon shift  $d_{FC}$  (a measure of defect-phonon coupling)

### DLOS and SSPC Measurement Conditions

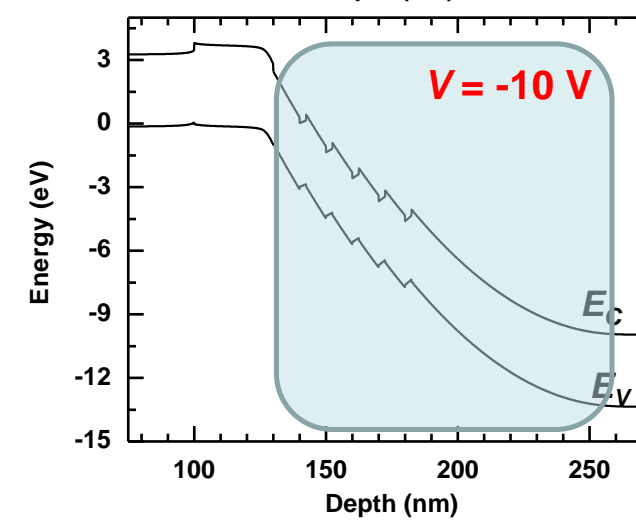
- Xe lamp and monochromator for  $h\nu = 1.20 - 3.60$  eV, 20 meV resolution
- 297 K, various fill and reverse biases for depth sensitivity
- Lock-in amplifier at 5 kHz

1. Chantre *et al.* PRB 23, 5335 (1981). 2. Paessler JAP 96, 715 (2004).

## Depth-resolved LED DLOS



V = 0 V: DLOS “sees” mostly the MQW region  
➤ Detect InGaN well and GaN barrier defects

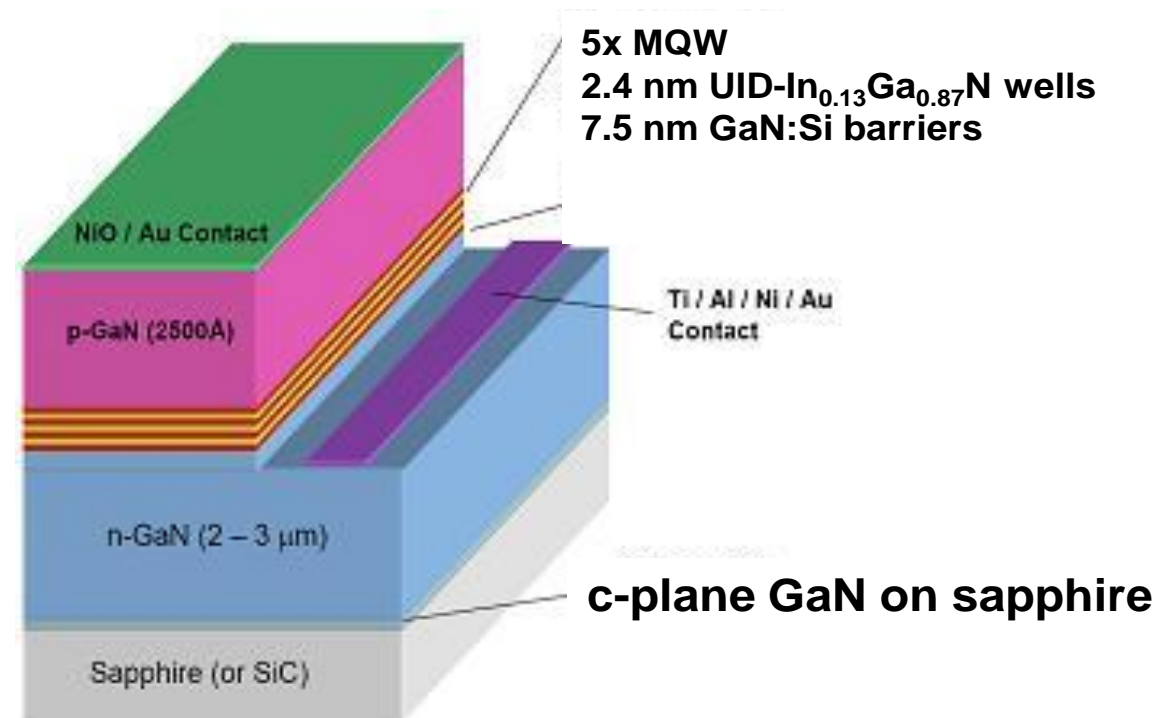


V = -10 V: DLOS “sees” MQW and n-GaN region  
➤ Weak sensitivity to InGaN well defects  
➤ Strong sensitivity to GaN defects

**DLOS at small and large reverse bias discerns GaN vs. InGaN defects in LEDs**

# Test case – Impact of Dislocations on InGaN/GaN LED EQE

## InGaN/GaN LED structure



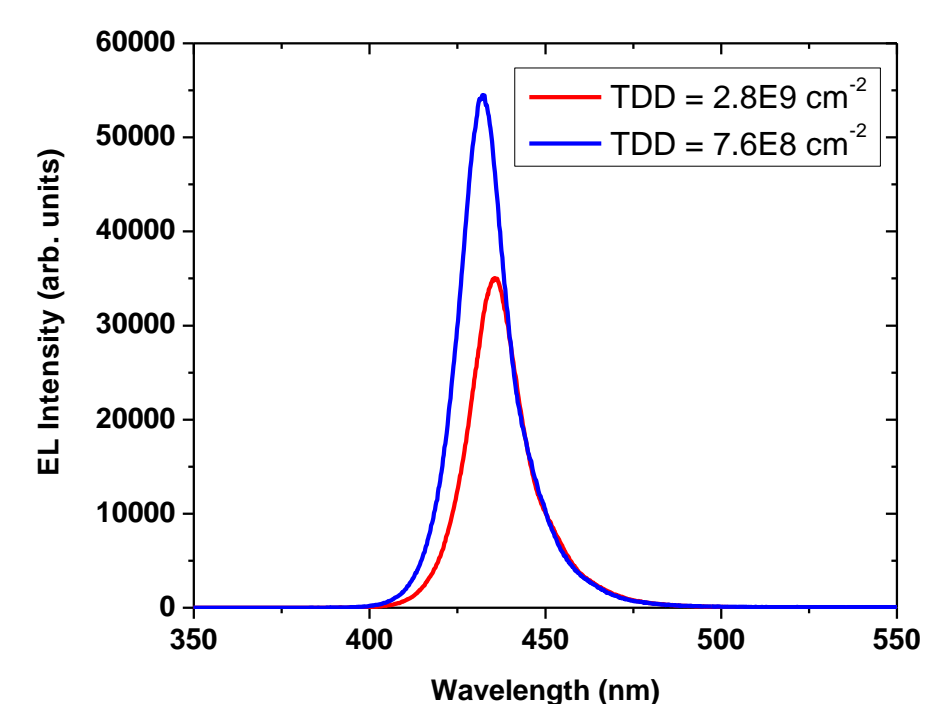
- MOCVD grown
- Threading dislocation density (TDD)  $\sim 7.6 \times 10^8 \text{ cm}^{-2}$  or  $2.8 \times 10^9 \text{ cm}^{-2}$
- TDD controlled by GaN nucleation and coalescence parameters<sup>1</sup>
- TDD measured via x-ray diffraction rocking curve analysis<sup>2</sup>

<sup>1</sup> M. F. Schubert, S. Chhajed, J. K. Kim, E. F. Schubert, D. D. Koleske, M. H. Crawford, S. R. Lee, A. J. Fischer, G. Thaler, and M. A. Banias, *Appl. Phys. Lett.* 91, 231114 (2007).

<sup>2</sup> S. R. Lee, A. M. West, A. A. Allerman, K. E. Waldrip, D. M. Follstaedt, P. P. Provencio, D. D. Koleske, and C. R. Abernathy, *Appl. Phys. Lett.* 86, 241904 (2005).

## LED characterization

TDD vs. EL for on-chip test devices

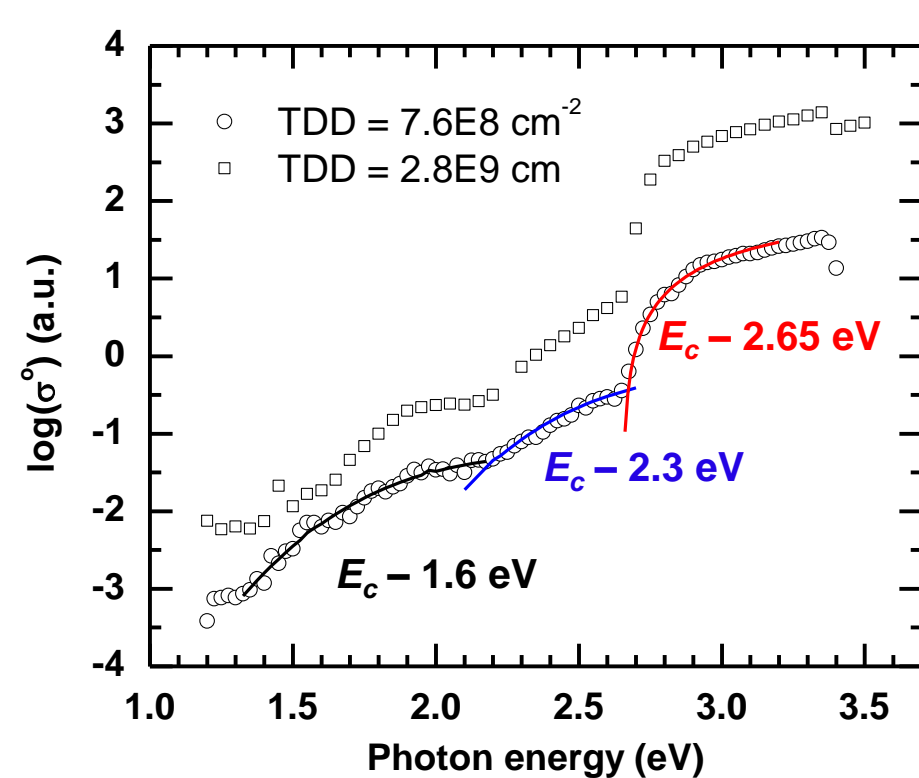


- 50% improved integrated electroluminescent (EL) intensity for lower TDD
- Relative EL intensity of on-chip test devices indicative of relative LED EQE
- Consistent with earlier reports, but details TDD role on EL unknown...

# MQW vs. n-region defects

## Survey of LED MQW region defects

-3 V DLOS

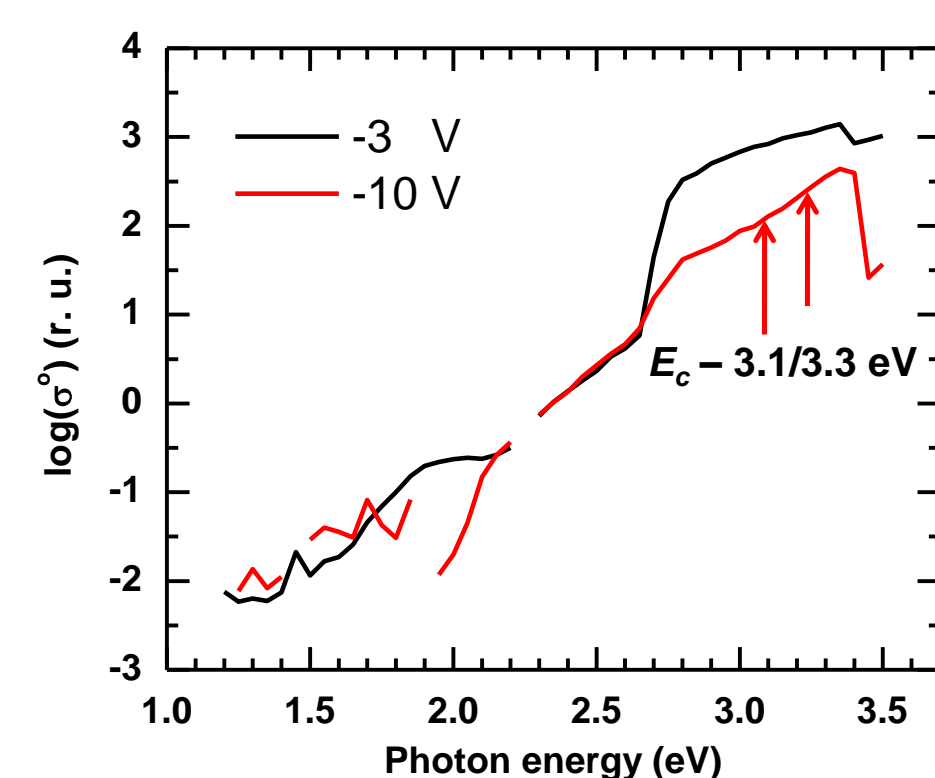


### Observe three defect states in MQW region:

- Similar defect states for both samples – no new defects with increased TDD
- $E_c - 2.65$  eV likely InGaN-related due to proximity to InGaN band edge
- Location of remaining defect levels unclear

## Survey of n-region defects

-3 V (MQW) vs. -10 V (MQW + n-region) DLOS

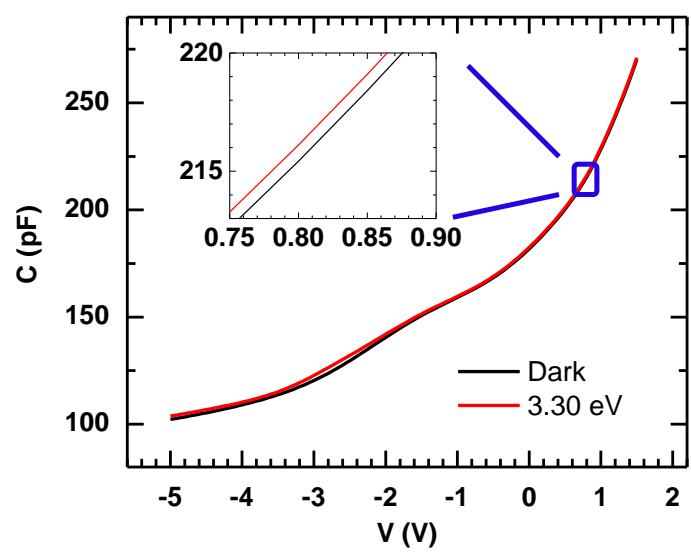


- New GaN-related defect levels at  $E_c - 3.1/3.3$  eV
- $E_c - 2.3$  eV level still evident – likely GaN-related
- No  $E_c - 1.6$  eV level – likely InGaN-related

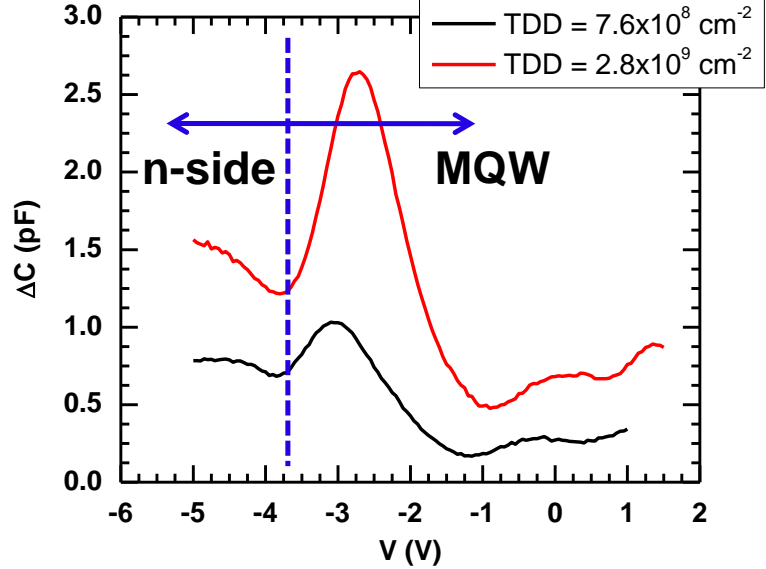
# Impact of TDD on Defect Density

## Measuring LED defect density

Lighted C-V for TDD = 7.6E8 cm<sup>-2</sup>



LCV comparison vs. TDD

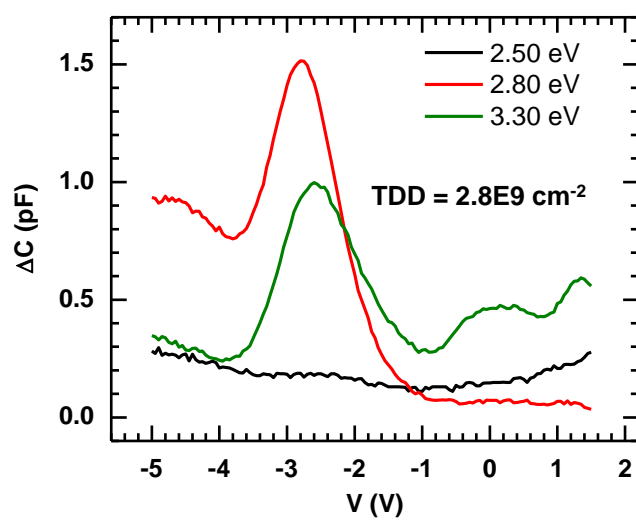


Lighted Capacitance-Voltage (LCV) measurements quantify defect density ( $N_t$ )

- Area under C-V curve proportional to space-charge density in LED junction
- Increase in capacitance with light ( $\Delta C$ ) results from defect photoionization
- Calculate average  $N_t$  from area under LCV curve

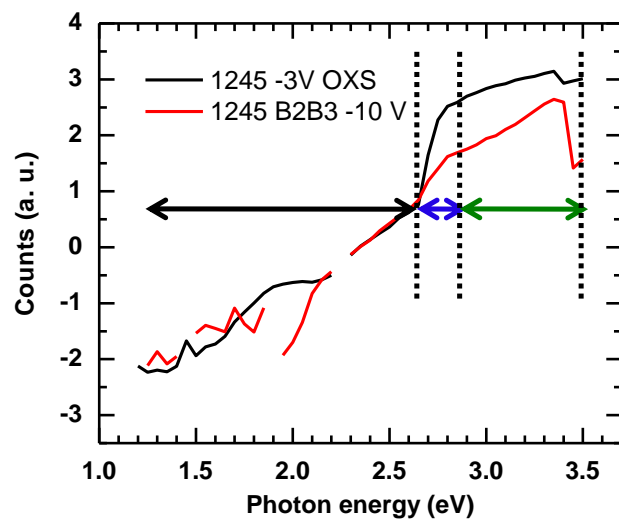
## LED defect density vs. TDD

LCV for individual defect states



Average  $N_t$  for MQW-region defect states

Defect Level (eV)	TDD = 7.6e8 cm <sup>-2</sup> $N_t$ (cm <sup>-3</sup> )	TDD = 2.8e9 cm <sup>-2</sup> $N_t$ (cm <sup>-3</sup> )	$\Delta N_t$
$E_c - 1.6/2.3$	8.8e14	3.2e15	3.6x
$E_c - 2.65$	1.8e16	3.2e16	1.8x
$E_c - 3.1/3.3$	3.7e15	1.4e16	4x



- Strong decrease in  $N_t$  with reduced  $N_t$  for both InGaN- and GaN-related defects
- Universal decrease in  $N_t$  suggests TDD impacts both point and extended defect density incorporation in LEDs

# Summary and Outlook

## Summary and Future Work

- First quantitative defect spectroscopy for InGaN LEDs
- Reducing TDD reduces point and extended defect incorporation in InGaN/GaN LEDs
- 50% enhancement of LED radiative efficiency with defect reduction

- Extend DLOS study to blue- and green-emitting LEDs
- Identify defects that correlate with reduced EQE with increase wavelength
- Systematic reduction in targeted defects to improve InGaN/GaN LED EQE at 540 nm

## Acknowledgement of Support



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